

Inventor: Kevin J. Torek et al.

Title: Methods of Removing Material from a Semiconductor Substrate

Assignee: Micron Technology, Inc.

**INFORMATION DISCLOSURE STATEMENT**  
**PURSUANT TO 37 C.F.R. " 1.56, 1.97 AND 1.98**

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a continuation application of co-pending application Serial No. 09/653,157, filed August 31, 2000. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated: April 12, 2004

By:

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Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2559	SERIAL NO. PRIORITY 09/653.157	
<b>LIST OF ART CITED BY APPLICANT</b> (Use several sheets if necessary)				APPLICANT Kevin J. Torek et al.		
				FILING DATE PRIORITY August 31, 2000		
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,810,978	09-1998	Nakatsuka et al.		
	AB	5,540,047	07-1996	Dahlheim et al.		
	AC	6,133,603	10-2000	Nomoto		
	AD	5,683,857	11-1997	Shirai et al.		
	AE	4,885,047	12-1989	Ury et al.		
	AF	5,632,868	05-1997	Harada et al.		
	AG	6,306,564	10-2001	Mullee		
	AH					
	AI					
	AJ					
	AK					
	AL					
FOREIGN PATENT DOCUMENTS						
	Document Number	Date	Country	Class	Subclass	Translation
						Yes    No
	AM	9-241007 (ABSTRACT)	09-1997	JAPAN		
	AN	JP411219926A	08-1999			
	AO					
	AP					
	AQ					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)						
	AR	ABSTRACT of Article: Voigt, K. et al., "A Little Nitrogen Goes a Long Way in Ozone Production...Or The Addition of Nitrogen Gas to Pure Oxygen Ozone Generators to Achieve Greater Generator Efficiency", 1994 Annual Conf. Proceedings, American Water Works Assn., New York, NY, June 19-23, 1994, pp. 885-900.				
	AS					
EXAMINER			DATE CONSIDERED			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						